

VIEW Pinnacle™ 250

A high throughput, high accuracy dimensional metrology system





Featuring:

250 x 150 x 100 mm (10 x 6 x 4 in.) measuring range

 E_2 (XY plane) = (1.5 + 5L/1000) μ m

400 mm/sec stage X,Y velocity with frictionless linear motor drives

Sub-micron scale resolution

High-precision dual magnification optical system

Optional through-the-lens (TTL) laser with autofocus and scanning capabilities

Advanced image processing for high speed, accuracy and robustness

Subpixel accuracy of 1/10 to 1/50 pixel

Choice of powerful metrology software and data analysis tools

MTBF 8,000 hours

Optional ESD and Class 1000 clean room compatible

Photo Description: VIEW Pinnacle 250
The photo above displays the Pinnacle 250 model with VMS software, and optional Integrated workstation. Additional options are listed in the technical specifications and are not included in this photo.



The VIEW Pinnacle[™] 250 delivers unmatched accuracy and throughput, MTBF performance, and the lowest cost of ownership for an automated measuring system of its kind. Its exclusive multi-color Programmable Ring Light (PRL) allows use of red, green, blue, or white LED light to effortlessly image the toughest applications.

State-of-the-art linear motion control technology provides the fastest, most reliable, and maintenancefree platform available for high volume, high capacity operation in production environments ranging from clean rooms to factory floors.

Available optional software packages increase system versatility:

- CAD import (DXF/IGES) Software
- Form fitting and analysis Software
- Off-line Programming Software
- QC-Calc™ Statistical Process Control (SPC) Real-time analysis and reporting software
- Elements™ CAD To Measure metrology software

Advanced metrology for leading technologies

Applications for Pinnacle include:

Semiconductor/Electronics

- BGA, μBGA, CSP, flip-chip, MCM, bump-on-die
- Lead frames, wire bonds, flex circuits, connectors
- SMT component placement
- Solder paste/Epoxy glue dot
- Chip carriers and trays
- Inkjet printer cartridges
- Fiber optic components and MEMs

Data Storage

- Suspensions
- Slider and Head Gimble Assemblies (HGA)
- Disk media substrates

Precision plastic molded and machined parts

- Dies and tooling
- Medical devices
- Fuel injection components
- Watch components

Technical Specifications - VIEW Pinnacle™ 250

250 x 150 x 100 mm (10 x 6 x 4 in.)

○ 0.1 µm (0.000004") Scale Resolution

Measuring Range

● 0.05 µm (0.000002") Zero expansion material

Standard

Optional

Stage Drive System DC servo, frictionless linear motor drives on X and Y axes

DC servo, rotary motor drive on Z axis

XY: 400 mm/sec; Z: 100 mm/sec. Stage Drive Velocity

O Non-linear 2D error corrections in X-Y plane Stage Error Mapping

25 kg (55 lbs) maximum load Stage Load Capacity

 Dual magnification, fixed lens optical system with 1X and 4X internal **Optical System**

magnifications.

5x/20x 25x/100x Objective Magnification 0.8x/3.2x 1x/4x2.5x/10x 10x/40x84 mm 34 mm 13 mm 32 mm 33 mm 30 mm Working Distance Field of View (mm) Low

8.3 x 6.2 6.8 x 5.1 2.7 x 2.0 1.3 x 1.03 0.6 x 0.5 0.27 x 0.20 1.9 x 1.4 1.5 x 1.2 High

Optical Accessories Ronchi Grid Projection

Illumination Programmable LED Illumination system for stage backlight and coaxial surface light

> Multi-color (red, blue, green, and composed white) LED Illumination Programmable Ring Light (PRL)

■ VectorLight[™] high-intensity programmable ringlight with white LEDs

Cameras Dual digital 1.4 megapixel monochrome cameras; 4:1 ratio

Image Processing ● Frame integration; 10:1 to 50:1 subpixeling

 CiC - Continuous Image Capture integrated with stage motion for on-the-fly high speed measurement

Sensor Options Through-the-lens (TTL) laser autofocus and scanning sensor

SpectraProbe™ high resolution chromatic sensor

Dedicated system controller with embedded Intel[®] 2.66 Ghz Quad CPU Controller Processor and Windows® operating system

Stand-alone Anthro Cart Operator workstation; 90 x 90 x 128 cm; 40 kg Operator Workstation

> Integrated adjustablesit / stand workstation arm, with independent height adjustment for monitor and keyboard that provides support for the flat panel display and peripherals

Display Monitors Single 20" LCD flat panel monitor, joystick, keyboard, and mouse

Dual 20" LCD flat panel monitors, joystick, keyboard, and mouse

Metrology Software VIEW Metrology Software (VMS)

■ Elements[™] CAD to Measure metrology software

VMS Off-Line Workstation Software

Mechanical Options Certified calibration standards and accessories

Fixture kits

Rotary Indexers

 ≥ 8,000 hours MTBF

115/230 VAC, 50/60 Hz, 700 W Power Supply

○ 18-22°C, (65-71°F) 30-80% humidity (non-condensing); vibration Rated Environment

<0.0015g below 15Hz

(W x D x H) - 795 x 953 x 1750mm (31.5 x 37.5 x 69 in.) System Dimensions

Crated: 771 kg (1,700 lbs) Uncrated: 635 kg (1,400 lbs) Weight

 \bigcirc E₂ (XY plane) = (1.5 + 5L/1000) μ m^{1,2,3,4} Measuring Accuracy at 20°C (68°F)

 \bullet E₂ (XY plane) = (1.0 + 5L/1000) μ m^{1,2,3,4} \bigcirc E₁ (Z-axis) = (1.4 + 5L/1000) μ m^{1,2,5}

Where L = measuring length in mm.

All specifications apply to a thermally stable machine and a certified artifact at 20°C.

1. Maximum rate of temperature change: 1° C / Hour.

2. Maximum vertical temperature gradient: 1° C / Meter.

3. At rated velocity with evently distributed load of 25KG.

4. X/Y area accuracy artifact: OVI grid retide or QVI linescale in the standard measuring plane is Garned as within 25mm of the worktable surface.

5. Z axis accuracy artifact: QVI step gage, interferometer or master gage blocks.